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## Comparative study of WSe<sub>2</sub> thin films synthesized via pre-deposited WO<sub>3</sub> and W

precursor material selenization

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## Abstract

Layered two-dimensional (2D) materials, such as p-type WSe<sub>2</sub>, are potential key materials in the manufacture of the next generation electronic devices. One of the remaining main challenges is the large area growth of high-quality films. A potential large-scale 2D WSe<sub>2</sub> synthesis method is conversion (selenization) of a pre-deposited sacrificial precursor coating. However, its use is still limited, mainly due to a lack of understanding the growth mechanisms involved. Here, we have studied and compared properties of thin crystalline WSe<sub>2</sub> films prepared via selenization of sputter-deposited sacrificial WO<sub>3</sub> and W films. Surface morphology of the as-grown films was studied using a scanning electron microscope complemented with an atomic force microscope. The structure and chemical composition were confirmed by X-ray diffraction and micro-Raman spectroscopy, respectively. On-chip photoconductive devices were made using the standard photolithography process, and their photoresponse was investigated with 405 nm wavelength light. For the electrical characterization, field effect transistors (FETs) were made to measure output and transfer curves. The results obtained give insight into the growth of crystalline WSe<sub>2</sub> via sacrificial film selenization.

## Keywords

B1. tungsten diselenide; B1. transitional metal dichalcogenides; A3. thin films; A3. chemical vapor transport; B3. Photolithography

## 1. Introduction

Transition metal dichalcogenides (TMDs) have gained quite a lot of attention in recent years, mainly due to their nature of being layered van der Waals (vdW) materials [1]. In bulk, they do not exhibit any exclusive characteristics for electronics applications, but when reduced to two-dimensional (2D) form, they have displayed unparalleled properties which are suitable for replacing the conventional semiconducting materials [2–6]. Exploring the potential applications of these semiconducting materials is currently an active topic of research which generally includes demonstration of their use in the fields of photovoltaic cells, field-effect transistors, phototransistors, production of H<sub>2</sub> via water splitting, Schottky diodes, and more [7–14]. The reason why these materials have sparked such research interest is the availability of intrinsic p-type and n-type of 2D materials. Most of the reported TMDs are n-type semiconductors (e.g. MoS<sub>2</sub>) by nature, however, WSe<sub>2</sub> is currently being studied extensively for its p-type characteristics [1,2,4,15–19]. Employing this property of WSe<sub>2</sub> and combining it with other n-type TMDs, using the weak vdW force, opens up possibilities for fabrication of the next generation of heterostructures [8–11,20–22].

WSe<sub>2</sub> has a crystal structure comprised of Se-W-Se layers weakly bonded via vdW force, generating a sandwich-like form. These three atomic layers are packed in hexagon shape, and in turn they make a monolayer of WSe<sub>2</sub> [23]. These layers of WSe<sub>2</sub> are highly prone to randomly distributed defects such as Se atom vacancy and W atom vacancy [5,24,25], which in turn affects the quality and the properties of the crystals. The electronic energy band structure of this material changes with the number of layers stacked on each other [26]. WSe<sub>2</sub> shows indirect bandgap when in the bulk state, but that changes to direct bandgap when number of layers is decreased to one [1]. To achieve this high quality of monolayer WSe<sub>2</sub>, various methods have been proposed and demonstrated including

different types of chemical vapour deposition (CVD) methods [14], pulsed-laser deposition (PLD) [27] and atomic layer deposition (ALD) [28].

In this work, we report the synthesis of  $WSe_2$  by the method of chemical vapour transport (CVT) in which we have used two different sources of pre-deposited sacrificial precursor films –  $WO_3$  and W metal. The reason for this study was to compare the synthesized  $WSe_2$  crystalline films from each precursor material and understand how they affect the different properties of the film. The CVT method is one of the most efficient, widely used, and up-scalable 2D material synthesis techniques available. Therefore,  $WSe_2$  films were also synthesized using that method, keeping in mind possible upscaling in the future. To showcase the photoelectric properties of the synthesized films, on-chip devices are also demonstrated.

## 2. Experimental details

## 2.1. Tungsten diselenide film synthesis:

Sacrificial precursor films with varying thicknesses, from 3 nm to 50 nm, were deposited on oxidized silicon wafers SiO<sub>2</sub>/Si (100) (Semiconductor Wafer, Inc.) by reactive DC magnetron sputtering of a metallic tungsten target in a mixed  $Ar/O_2$  atmosphere (5·10<sup>-3</sup> torr, 30 sccm Ar, and 20 sccm O<sub>2</sub> gas flow at 300 W DC power). After the precursor material deposition, synthesis of WSe<sub>2</sub> was performed from W metal film and WO<sub>3</sub> film using CVT. The CVT setup consists of a horizontal open-end quartz tube reactor. For the procedure, selenium powder was loaded in a ceramic boat at one end of the quartz tube. The vapour of selenium was transported downstream to the W/WO<sub>3</sub> precursor material on a silicon substrate using the carrier gas mixture: 5% Ar/H<sub>2</sub> in the

case of WO<sub>3</sub> and 35% Ar/H<sub>2</sub> in the case of W. The temperatures (ranging from 600 to 850 °C) were held constant for 20 min, followed by uninterrupted cooling to the room temperature.

The synthesized films were studied under a scanning electron microscope (SEM-FIB Lyra, Tescan) and a Park NX10 (Park Systems) atomic force microscope (AFM) for the surface morphology. The phase compositions of the samples were studied using X-ray diffraction (XRD, powder diffractometer Rigaku Miniflex 600) with monochromatic Cu K $\alpha$  irradiation ( $\lambda = 1.5406$  Å), and the spectra were analysed using PDXL2 software. Micro-Raman spectroscopy measurements were performed using a TriVista 777 confocal Raman system (Princeton Instruments) equipped with an upright Olympus microscope with an Olympus UISe MPlanN 100x/0.90 objective, a continuouswave single-frequency diode-pumped laser Cobolt Samba 150 ( $\lambda = 532$  nm), and an Andor iDus DV420A-OE CCD camera. For the electrical characterization, silicon substrates (100) with a 300 nm oxide layer (Semiconductor Wafer, Inc.) were used with a separate design configuration, and the measurements were carried out using two (Keithley 2400) source-meter units. Transfer characteristics (I<sub>DS</sub>-V<sub>GS</sub>) were measured at gate voltages ranging from +30V to -30V and sourcedrain voltages of 0V to 5V, with a total acquisition time of 24 seconds for each curve. Output characteristics (I<sub>DS</sub>-V<sub>DS</sub>) were measured similarly with gate bias voltages ranging from 0V to -20V and source-drain voltages ranging from 0V to 5V, with a total acquisition time of 24 seconds for each output curve.

### 2.2 On-chip photosensor device fabrication:

Fabrication of on-chip devices had a few extra steps involved compared to the synthesis of plain  $WSe_2$  films on silicon samples. The steps are graphically illustrated in *Fig. 1*. Using the conventional photolithography (spin-coating, exposure, development), the first layer of mask was created for depositing the precursor material in specific regions with magnetron sputtering. After deposition of

the desired precursor material, the mask was removed applying the standard lithography lift-off procedure. Conversion from precursor material W/WO<sub>3</sub> to WSe<sub>2</sub> took place afterwards using the CVT method, and then another mask was deposited on top of the WSe<sub>2</sub> films using the previously used standard lithography process for the deposition of the electric contacts to fabricate the on-chip devices. These fabricated devices were used for the photoelectric measurements.



**Fig. 1.** Schematic of the process of on-chip device fabrication. First the SiO<sub>2</sub>/Si substrate is cleaned using acetone and isopropanol (a), then the first mask is made using the standard photolithography process (b) on which precursor material is deposited (c). After first mask lift-off, the precursor material film is in the desired pattern (d) which is subsequently selenized (e). Afterwards, the second photoresist mask is deposited (f) for the deposition of contact material ( $Cr \sim 5$  nm,  $Ag \sim 95$  nm,  $Al \sim 50$  nm) using the thermal evaporation method (g) followed by lift-off to obtain the photoconductor device array on a chip (h).

## 2.3 Device measurements:

Photoresponse and the current-voltage (I-V) curves were measured for the fabricated devices using a two-contact microprobe station connected to a low-noise current preamplifier (SR570, Stanford

Research Systems) and an oscilloscope (TDS2004B, Tektronix). A 405 nm wavelength semiconductor diode laser (CNI Laser) with 1 W/cm<sup>2</sup> was the illumination source for the photo-response measurements. An optical beam shutter (Thorlabs SH05) was used for time-resolved measurements. All the measurements were performed at room temperature and in air.

## 3. Results and discussion

Various thicknesses of the deposited precursor materials (WO<sub>3</sub> and W) ranging from 3 nm to 40 nm



**Fig. 2.** Scanning electron microscope images at different magnifications of WSe<sub>2</sub> films made from a WO<sub>3</sub> precursor at 700 °C (a,b) and 800 °C (c,d) and from a W metal precursor at 700 °C (e,f) and 800 °C (g,h).

were tested. The attempt to make a 3 nm film resulted in forming an island structure instead of a

continuous film. Optimally, the continuous and homogeneous yet thinnest films were about 10 nm

in thickness and above. SEM was used to study the as-grown  $WSe_2$  film's morphology. Films

synthesized from the WO<sub>3</sub> precursor material typically had larger crystals, reaching up to a diameter

of 1 µm at a high temperature (800 °C), while at a lower temperature (700 °C), the crystals did not

seem to have distinctive boundaries (see Fig. 2(a-d)). Above 800 °C the films started to sublimate,

while below 700 °C the films showed no formation of  $WSe_2$  crystals. However, for the films made

from a W metal precursor, the crystals demonstrated distinctive boundaries, but they were

comparatively smaller in size – growing up to the diameter of 0.5  $\mu$ m regardless of the CVT process

temperature (see Fig. 2(e-h)). WSe<sub>2</sub> films also had a distinctive difference in the average crystals



**Fig. 3.** Atomic force microscope (AFM) Z-drive images of  $WSe_2$  films made from a  $WO_3$  precursor (a) and from a W metal precursor (c) showing the difference between film surfaces and further complimented by SEM images of the same samples in the respective order of (b) and (d).

size. On average, crystals grown from the W metal precursor were of similar diameter (0.3 - 0.5

 $\mu$ m), whereas the crystals grown from the WO<sub>3</sub> precursor had a significant variance in diameter (0.2

- 1.5  $\mu m).$  The reason for the larger out-of-plane  $WSe_2$  crystal growth at 700-800 °C compared to

the W metal species is presumably due to the higher volatility and diffusivity of the WO<sub>3</sub> species. Furthermore, the surface morphology of the films depends on the precursor material, which is visible in AFM images and complemented by SEM images (*see Fig. 3*). WSe<sub>2</sub> films synthesized from the WO<sub>3</sub> precursor material showcased more crystals growing out-of-plane compared to the films synthesized from W metal precursor. Z-drive images (*Fig. 3(a,c)*) obtained from AFM, show a few crystals coming out in random distribution, whereas the film grown from W metal has better distribution of crystals with a comparatively flatter surface. This out-of-plane crystal growth could be caused by evaporation of the WO<sub>3</sub> precursor film followed by selenization in the vapour phase



**Fig. 4.** X-ray diffraction patterns of WSe<sub>2</sub> films from both precursors (WO<sub>3</sub> and W) at different temperatures, 700 °C and 800 °C, show peaks confirming the phase of the synthesized WSe<sub>2</sub> film. and as-formed WSe<sub>2</sub> re-deposition, leading to growth of crystals.

The presence of different phases in WSe<sub>2</sub> films on Si(100)/SiO<sub>2</sub> were checked using XRD measurements. *Fig. 4* shows the XRD patterns for films synthesized from WO<sub>3</sub> and W metal at different temperatures of 700 °C and 800 °C. All patterns indicate crystalline films of WSe<sub>2</sub> (ICDD-



Fig. 5. Raman spectra of WSe<sub>2</sub> thin films synthesized from both precursors (WO<sub>3</sub> and W) using CVT method showing the peaks respective to  $E^{1}_{2g}$  and  $A_{1g}$  vibrational modes.

PDF #38-1388). No other phases were detected during the measurement. In *Fig. 4*, the peak at 33° is ascribed to the diffraction in the Si(100) substrate (forbidden Si(200)) reflection). To compliment these results, room temperature micro-Raman measurements were also performed on the synthesized films. The Raman peaks (*Fig. 5*) observed around 250.2 and 259 cm<sup>-1</sup> are attributed to the in-plane ( $E^{1}_{2g}$ ) and out-of-plane ( $A_{1g}$ ) vibrational modes of WSe<sub>2</sub>, therefore confirming the formation of WSe<sub>2</sub> [26]. XRD patterns and Raman measurements of as-grown films confirm the conversion of precursor materials to WSe<sub>2</sub> crystals using the CVT process, which makes it a viable method to obtain WSe<sub>2</sub> thin films.

As shown in Fig. 6(a,b), in the first, step various sized continuous WSe<sub>2</sub> films were prepared using

photolithography to make devices with varying gap widths between the two electrodes, ranging



Fig. 6. Optical images of the synthesized patterned  $WSe_2$  films made by photolithography (a,b), and devices with various gap widths between the two electrodes were fabricated (c-e) using  $WSe_2$  films.

from 250 µm to 2 µm (Fig. 6(c-e)). Fig. 7(a-c) shows the photoelectric characteristics of the WSe<sub>2</sub>

films synthesized from WO3, and Fig. 7(d-f) shows the photoelectric characteristics of the films

synthesized from W metal precursor. Dark state current-voltage (I-V) for both the films can be seen

to exhibit linear behaviour, suggesting that Ohmic contacts may have been formed. The devices

were illuminated with a 405 nm wavelength light source in a periodic fashion to study their photo-

response properties, as shown in Fig. 7(e,h). The devices were also tested with 532 nm and 660 nm



light. However, no sensitivity from the devices was observed. On-off measurements demonstrate a rapid and repeatable increase and decrease of current (rise and fall times), below 20 ms, when the

**Fig. 7.**  $WSe_2$  two-terminal photoconductor devices prepared from  $WO_3$  and W metal as the precursor materials, respectively, showing dark state I–V characteristics (a,d), on-off response (b,e), and response time (c,f) measurements at 2 V bias voltage and 1 W/cm<sup>2</sup> light intensity with a 405 nm wavelength light source.

light source is turned on and off, respectively. This demonstrates good reversibility of the devices. Furthermore, it was observed that WSe<sub>2</sub> film made from the W metal precursor did not exhibit stable persistent photocurrent. When exposed to light, transient current can be observed, quickly followed by return to dark current level. Similarly, when the light source is turned off, it shows similar behaviour with a negative transient current at the start. This transient current can occasionally be observed for nanoscale photodetector devices, and it is attributed to charge trapping/de-trapping in semiconductor/electrode interfaces and to space-charge effects [29,30].

 $WSe_2 2D$  crystals are highly prone to various defects [5,24], such as selenium vacancies, which have been shown to degrade photoelectric properties of  $WSe_2$  [31]. These defects might cause the poor photoelectric performance for devices made from a W precursor. On the other hand, the films made



Fig. 8. WSe<sub>2</sub> two-terminal photoconductor devices, prepared from WO<sub>3</sub> and W metal as the precursor ( $I_{DS}$ -drain source current,  $V_{DS}$ -drain source bias voltage,  $V_{GS}$ - gate source bias voltage)

from a WO<sub>3</sub> precursor material exhibit better photoelectric properties because WO<sub>3</sub> might be providing oxygen impurities during the formation of the crystals. Selenium vacancy passivation with oxygen atoms has been previously demonstrated to restore/enhance photodetector performance [31]. In contrast, films made from W metal lack such oxygen atoms to passivate the selenium vacancies, leaving the films with degraded photoelectric properties.

For the electrical characterization of these films, field effect transistors (FETs) were made to measure the output and transfer curves (see Fig. 8). The output curve (*Fig 8(a)*) for W metal films

converted to WSe<sub>2</sub> has a minor reaction to the gate bias potential, which suggests incomplete conversion of W film to WSe<sub>2</sub>. The remaining metal phase is acting as a shunt resistance for the semiconducting layers of Wse<sub>2</sub>. Transfer curves (*Fig*  $\delta(b)$ ) at higher V<sub>DS</sub> and negative V<sub>GS</sub> can be noticed to have conductivity enhancement caused by the field-effect of WSe<sub>2</sub> layers, thus indicating that a majority of the charge carriers in these layers are holes. *Fig.*  $\delta(c,d)$  represents the output and transfer characteristics of the WSe<sub>2</sub> sample converted from the WO<sub>3</sub> precursor material. These devices exhibit a much stronger field-effect compared to the previous sample, and negative 'ON' voltage indicates p-type conductivity. Nonlinear behaviour of the output curves between -5 V and -10 V gate voltage (*Fig*  $\delta(c)$ ) can be caused by a small Schottky barrier at the metal/semiconductor junction due to the difference between the work function of Cr and WSe<sub>2</sub>. Lowering V<sub>GS</sub> from +30 V to -30 V results in an increase of I<sub>DS</sub> by 95.9% at 5 V source-drain voltage (*Fig*  $\delta(d)$ ) compared to 31.6% for the *Fig*  $\delta(b)$ . This indicates that the synthesis via CVT of WSe<sub>2</sub> from precursor WO<sub>3</sub> is better compared to W for the electrical properties as well.

## 4. Conclusions

In this work, we demonstrated, for the first time, a comparison of WSe<sub>2</sub> thin films made from two different pre-deposited precursor materials, WO<sub>3</sub> and W metal, using the CVT method at atmospheric pressure. As found during the characterization, SEM and AFM images showed the films grown from the W metal precursor had significantly lower surface roughness than the films grown from the WO<sub>3</sub> precursor. For the films made from the W precursor, crystal sizes were noticeably smaller (~0.4  $\mu$ m) in comparison to the films made from WO<sub>3</sub> (~0.8  $\mu$ m) which had crystal growth in a random orientation. Photoelectric measurements revealed that, despite having the out-of-plane crystal growth on the film from the WO<sub>3</sub> precursor, WO<sub>3</sub> films showed higher

photocurrent and stability, which was not the case with planar crystals grown from the W metal precursor. From the point of view of electrical properties, both films exhibited p-type conductivity. However, the films made from the WO<sub>3</sub> precursor showed better performance compared to the films made from the W metal precursor; indicating that WO<sub>3</sub> is a better precursor material than W metal when using the CVT approach for the synthesis of WSe<sub>2</sub>.

## **Declaration of competing interest**

There are no conflicts of interest to declare.

## **Credit authorship contribution statement**

Kevon Kadiwala: Methodology, Validation, Investigation, Visualization, Writing - original draft. Edgars Butanovs: Methodology, Investigation, Writing – review & editing. Martins Zubkins: Investigation. Andrejs Ogurcovs: Investigation. Boris Polyakov: Conceptualization, Supervision, Investigation, Writing - review & editing.

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## **Highlights:**

- Chemical vapor transport synthesis of WSe<sub>2</sub> from pre-deposited WO<sub>3</sub> and W precursor films
- Surface morphology and structure of as-prepared WSe<sub>2</sub> films were studied and compared
- Two-terminal photoconductor devices were fabricated and characterized

### **CRediT** authorship contribution statement

**Kevon Kadiwala:** Methodology, Validation, Investigation, Visualization, Writing - original draft. **Edgars Butanovs:** Methodology, Investigation, Writing – review & editing. **Martins Zubkins:** Investigation. **Andrejs Ogurcovs:** Investigation. **Boris Polyakov:** Conceptualization, Supervision, Investigation, Writing - review & editing.